



#5/IDS Division  
12-11-01

Sheet 1 of 2

U.S. Department of Commerce, Patent and Trademark Office				Atty Docket No.		Serial No.		
				M-9367 US		09/788,273		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant(s)				
(Use several sheets if necessary)				Borden, Peter G.; Li, Ji-Ping				
				Filing Date		Group		
				February 16, 2001		<del>2812</del> 2823		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
<i>RAE</i>	AA	4,255,971	3/17/1981	Rosencwaig	73	606		
<i>RAE</i>	AB	4,579,463	4/1/1986	Rosencwaig et al.	374	57		
<i>RAE</i>	AC	4,632,561	12/30/1986	Rosencwaig et al.	356	432		
<i>RAE</i>	AD	4,636,088	1/13/1987	Rosencwaig et al.	374	5		
<i>RAE</i>	AE	4,750,822	6/14/1988	Rosencwaig et al.	356	445		
<i>RAE</i>	AF	4,854,710	8/8/1989	Opsal et al.	356	432		
<i>RAE</i>	AG	4,950,990	8/21/1990	Moulder et al.	324	224		
<i>RAE</i>	AH	4,952,063	8/28/1990	Opsal et al.	356	432		
<i>RAE</i>	AI	5,042,951	8/27/1991	Gold et al.	356	369		
<i>RAE</i>	AJ	5,042,952	8/27/1991	Opsal et al.	356	432		
<i>RAE</i>	AK	5,159,412	10/27/1992	Willenberg et al.	356	445		
<i>RAE</i>	AL	5,181,080	1/19/1993	Fanton et al.	356	381		
<i>RAE</i>	AM	5,228,776	7/20/1993	Smith et al.	374	5		
<i>RAE</i>	AN	5,667,300	9/16/1997	Mandelis et al.	374	43		
<i>RAE</i>	AO	6,049,220	4/11/2000	Borden et al.	324	765		
<i>RAE</i>	AP	6,054,868	4/25/2000	Borden et al.	324	752		
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
<i>RAE</i>	AQ	WO 97/08536	6 March 1997	PCT	G01N	21/00		
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
<i>RAE</i>	AR	Amirtharaj and Seiler, "Optical Properties of Semiconductors," Handbook of Optics, Vol. II, McGraw-Hill, Inc., 1995, pp. 36.67-36.68, 36.95 and Table 11. (Exerpt).						
<i>RAE</i>	AS	Borden, Peter G. et al., "Evaluating A Property of A Multilayered Structure," U.S. Patent Application No. 09/521,232, filed on 3/8/00.						
Examiner		<i>Michelle Estrada</i>		Date Considered		3/13/03		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
<i>ME</i>	AT	Eikelboom, J.A. et al., "Microwave Detection of Minority Carriers in Solar Cell Silicon Wafers," <u>Solar Energy Materials and Solar Cells</u> , Elsevier Science B.V., Oct. 1995, pp. 169-185.	
<i>ME</i>	AU	Grove, A.S., "Physics and Technology of Semiconductor Devices," John Wiley & Sons, Inc., 1967, p. 326.	
<i>ME</i>	AV	Jackson, John David, "Classical Electrodynamics," John Wiley & Sons, Inc., 1962, pp. 222-226.	
<i>ME</i>	AW	Kolzer, J. et al., "Thermal Imaging and Measurement Techniques for Electronic Materials and Devices," <u>Microelectronics Engineering</u> , vol. 31, 1996, pp. 251-270, XP004006637, Elsevier Publishers BV., Amsterdam, NL, ISSN: 0167-9317.	
<i>ME</i>	AX	Martinsons, Christophe et al., "Recent progress in the measurement of the thermal properties of hard coatings," <u>Thin Solid Films</u> , vol. 317, April 1998, pp. 455-457, XP004147705, Elsevier-Seqoia S.A. Lausanne, CH, ISSN: 0040-6090.	
<i>ME</i>	AY	Opsal et al., "Thermal-Wave Detection and Thin-Film Thickness Measurements with Laser Beam Deflection," <u>Applied Optics</u> , Vol. 22, No. 20, Oct. 1983, pp. 3169-3176.	
<i>ME</i>	AZ	Orton, J.W. et al., "The Electrical Characterization of Semiconductors: Measurement of Minority Carrier Properties," Academic Press, 1990, pp. 94-100.	
<i>ME</i>	BA	Paquin, "Properties of Metals," <u>Handbook of Optics</u> , Vol. II, McGraw-Hill, Inc., 1995, pp. 35.3-35.7 (Exerpt).	
<i>ME</i>	BB	Rosencwaig, Allan et al., "Detection of thermal waves through optical reflection," <u>Appl. Phys. Lett.</u> 46, June 1985, pp. 1013-1015.	
<i>ME</i>	BC	Rosencwaig, Allan, "Thermal Wave Characterization and Inspection of Semiconductor Materials and Devices," <u>Photoacoustic and Thermal Wave Phenomena in Semiconductors</u> , Chapter 5, pp. 97-135, North-Holland, 1987.	
<i>ME</i>	BD	Rosencwaig, Allan, "Thermal-Wave Imaging," <u>Science</u> , Vol. 218, No. 4569, Oct. 1982, pp. 223-228.	
<i>ME</i>	BE	Schroder, Dieter K., "Semiconductor Material and Device Characterization," John Wiley & Sons, Inc., 1990, pp. 2-20, 84-85, 232-235, 304-306, 364, 367-374, 378-383.	
<i>ME</i>	BF	Sze, S.M., "Physics of Semiconductor Devices," John Wiley & Sons, Inc., 1981, pp. 50-51.	
<i>ME</i>	BG	"Process Monitoring System," Quantox Product Brochure, 3 pgs.	
Examiner <i>Michelle Estrada</i>		Date Considered <i>3/13/03</i>	
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